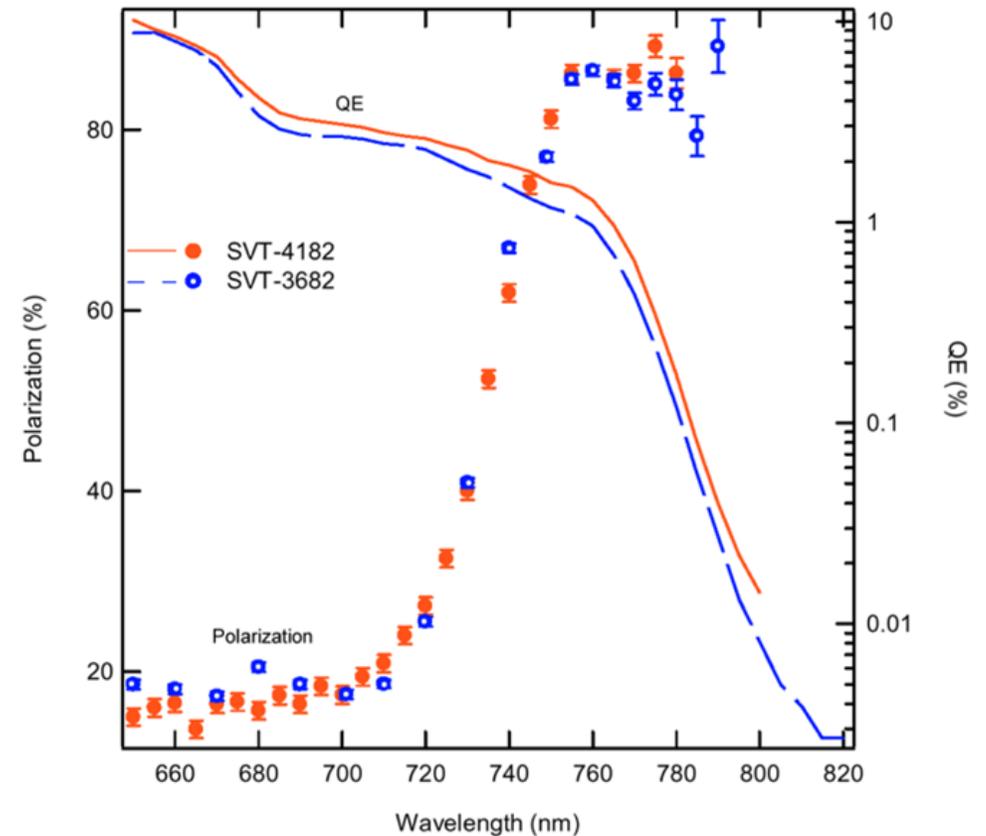


# Investigation into chemical beam epitaxy (CBE) for high polarization strained superlattice GaAs/GaAsP photocathodes

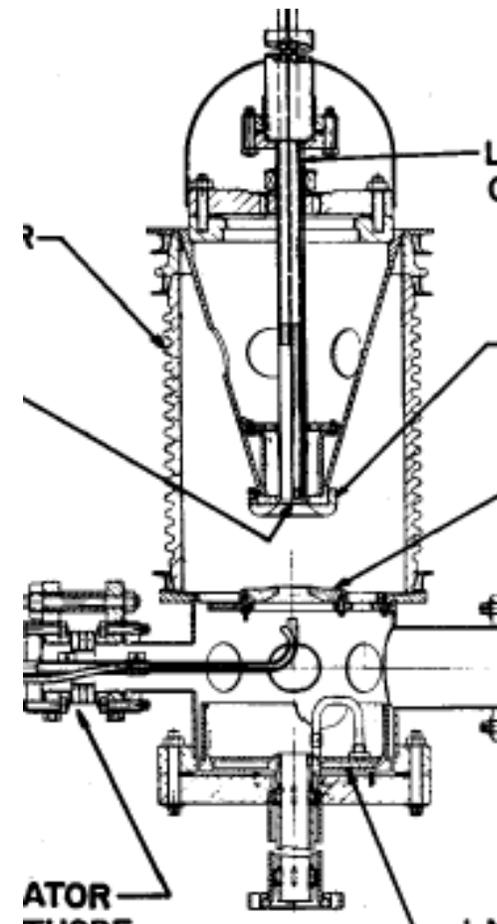
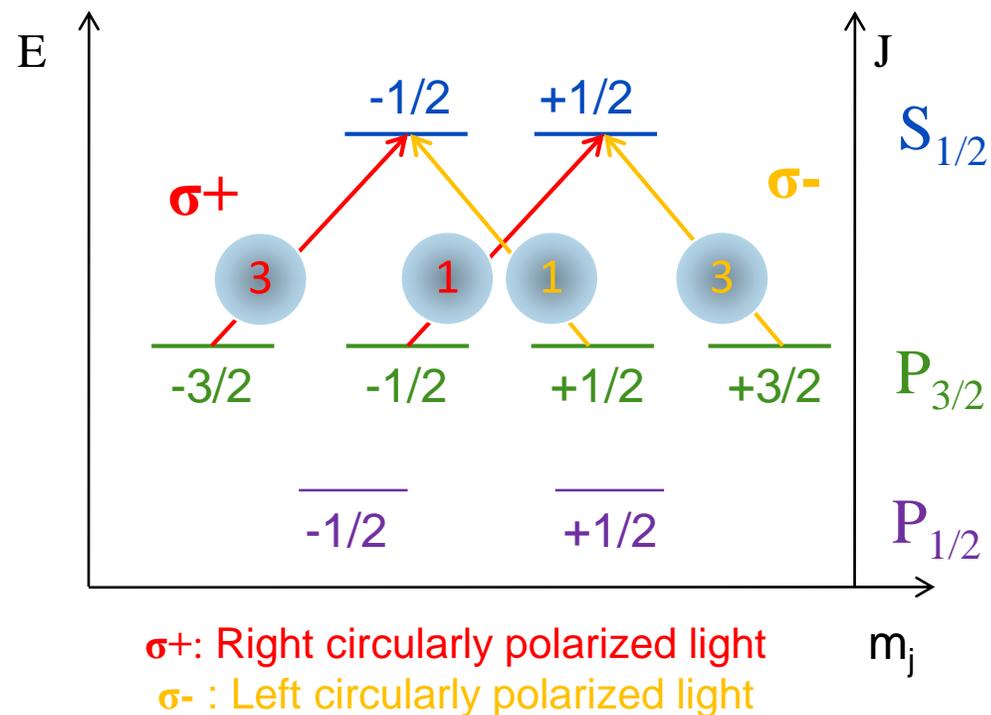
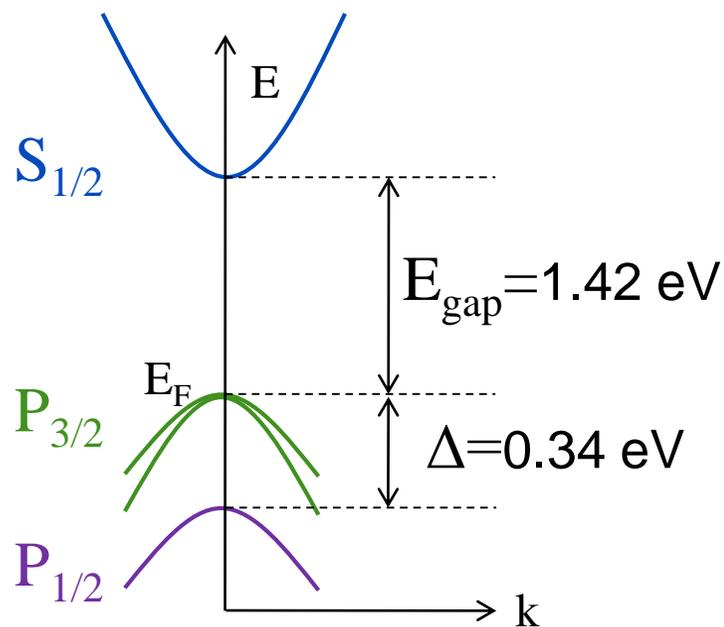
Annual NP Accelerator R&D  
and AI/ML PI Meeting  
November 30, 2021

Marcy Stutzman, Jefferson Lab  
Chris Palmstrøm and Aaron Engle, UCSB

Jefferson Lab



# Spin Polarized Photoemission from Bulk GaAs

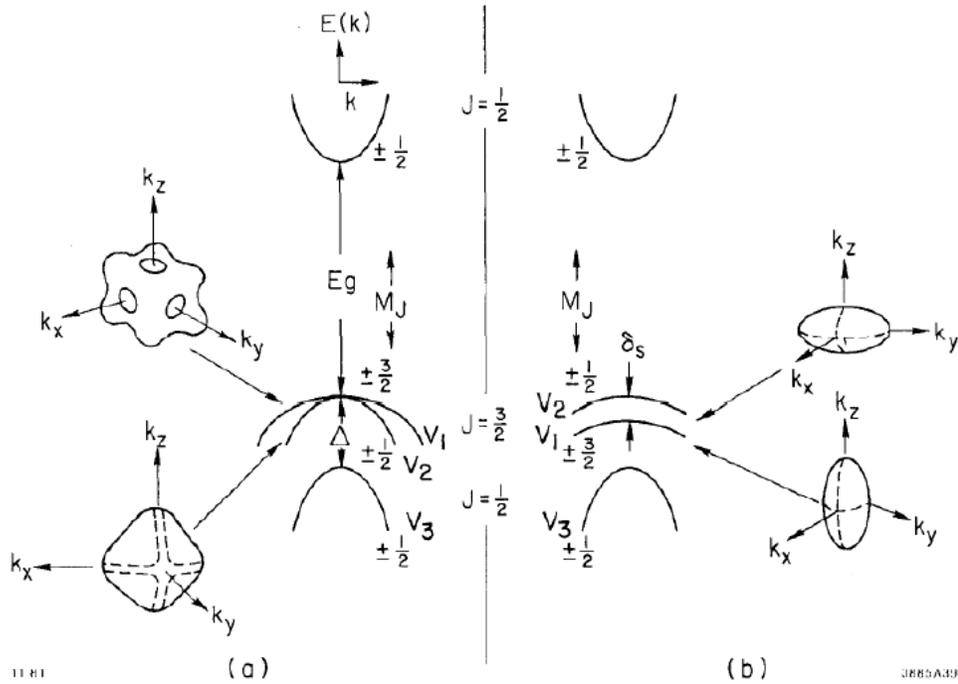


SLAC 1977

# Strained GaAs

## Breaking the 50% barrier

PhD thesis, Paul Zorabedian, SLAC Report 248, 1982



Application of a uniaxial strain removes the degeneracy of the  $P_{3/2}$  state

## Eliminate degeneracy of $P_{3/2}$ state via “Interface Stress Method”

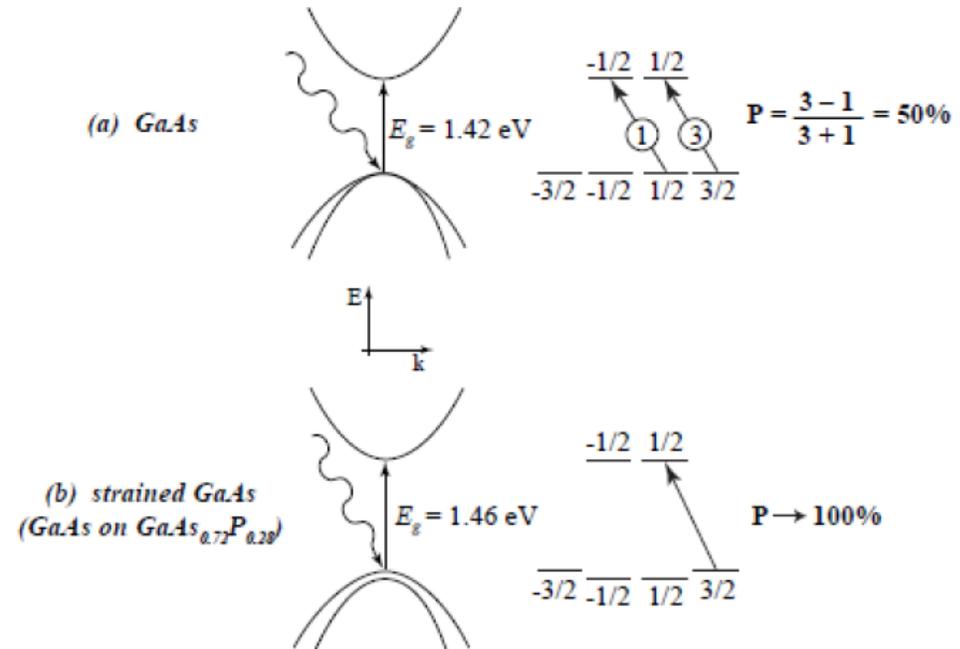
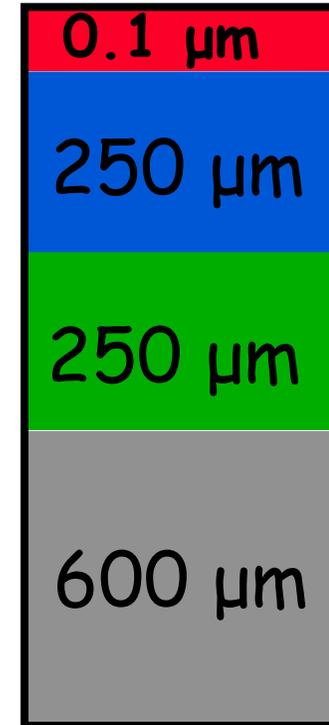
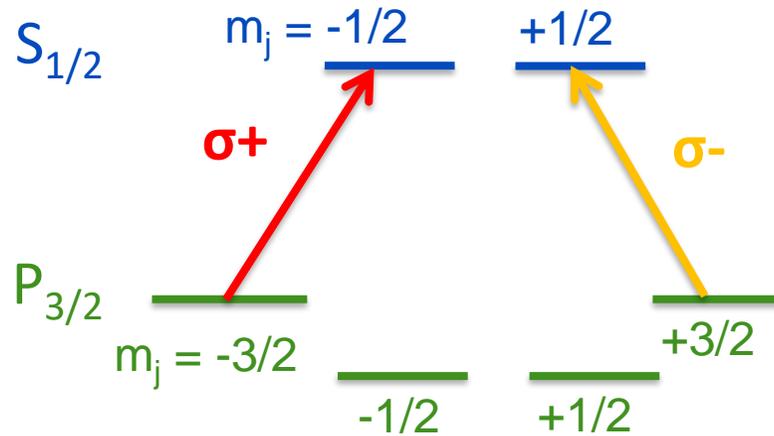


Image from Pablo Saez, PhD Thesis, Stanford University, SLAC Report 501, 1997

# Strained layer GaAs



0.1  $\mu\text{m}$  Strained GaAs

250  $\mu\text{m}$   $\text{GaAs}_{1-x}\text{P}_x$  ( $x=0.29$ )

250  $\mu\text{m}$   $\text{GaAs}_{1-x}\text{P}_x$  ( $0 < x < 0.29$ )

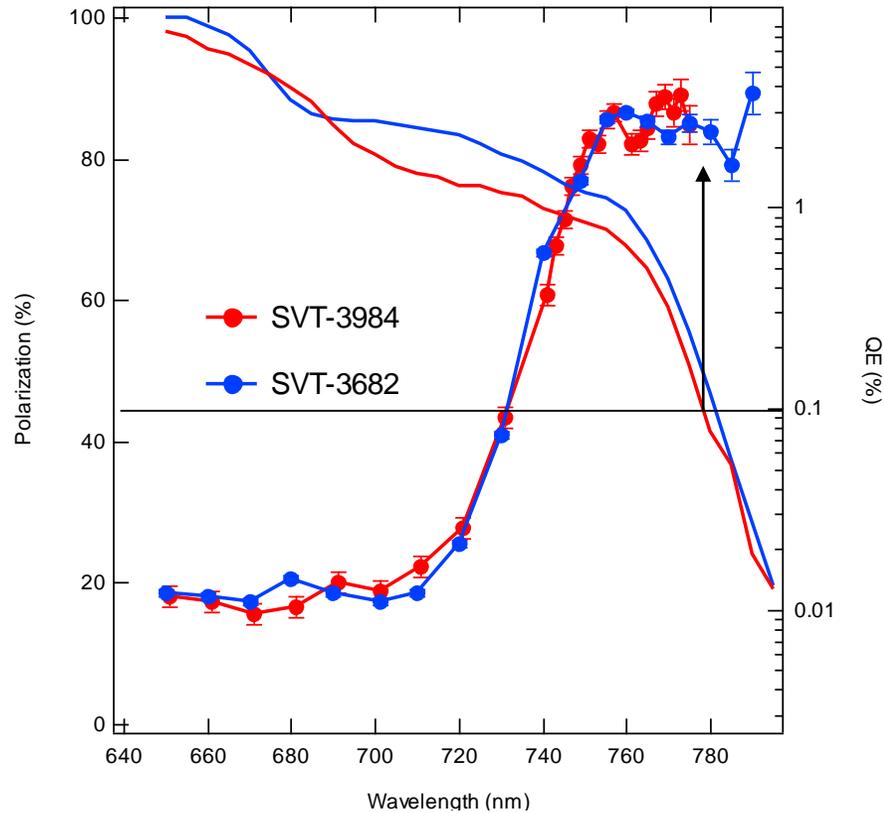
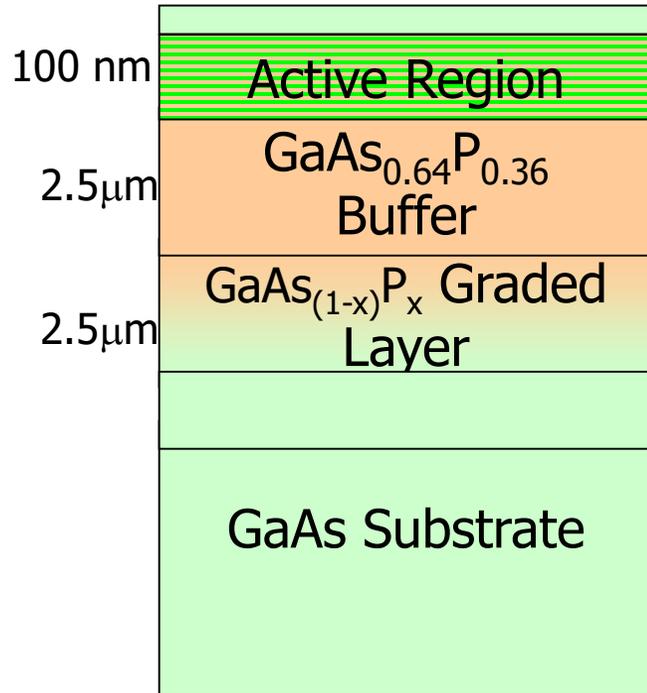
600  $\mu\text{m}$  p-type GaAs substrate

- ✓ Polarization 75%  $\gg$  50% ☺
- ✓ Strain relaxes in 100 nm layer
- ✓ QE 0.1%

MOCVD-grown epitaxial spin-polarizer wafer

Maruyama et al., Phys. Rev. B, **46** 4261 (1991)

# Strained layer superlattice GaAs/GaAsP



D. Luh et al, SLAC, PESP2002

QE 1% and Polarization 85%



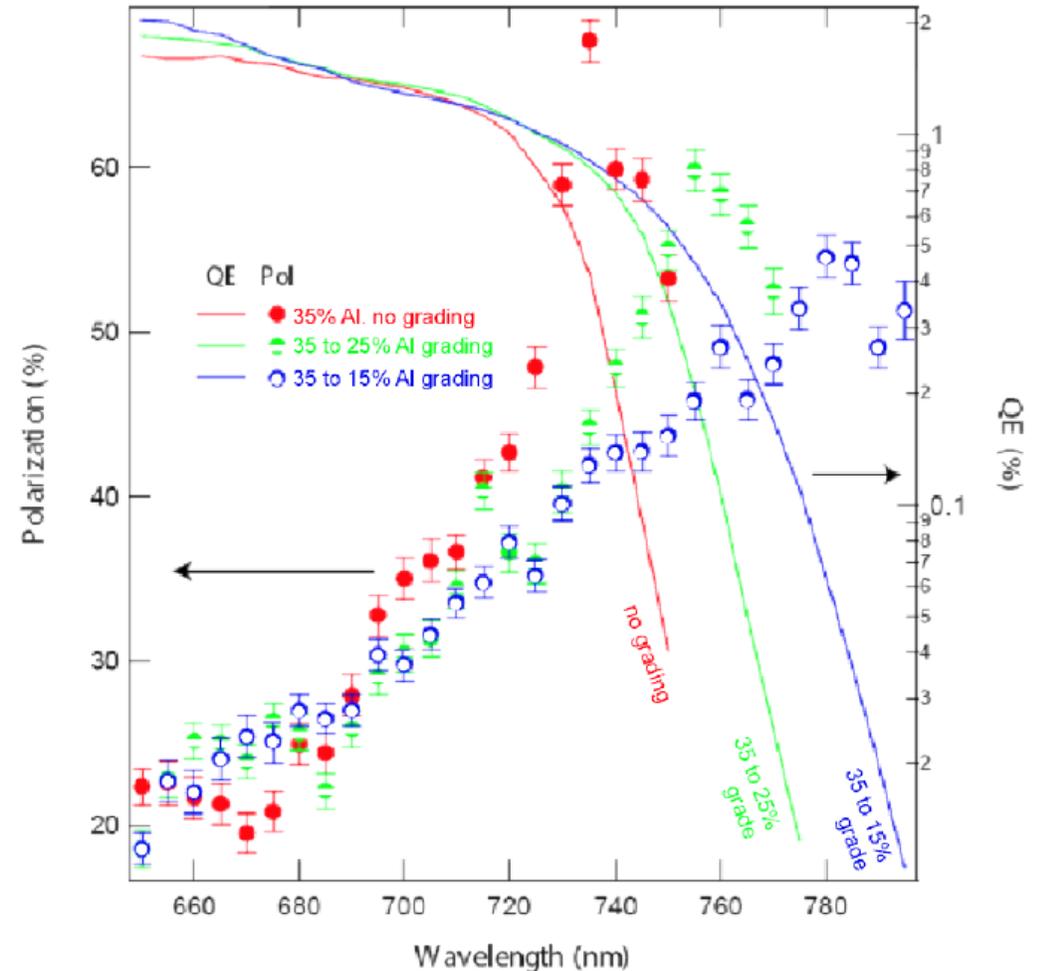
From Aaron Moy, SVT Assoc and SLAC, PESP2002

# Innovation through SBIR program

- SVT SBIR Partnerships with SLAC or JLab for high polarization photocathodes:
  - Phase I: 2001, 2005, 2007, 2012, 2013
  - Phase II: 2002, 2008, 2013, 2014
- Various Superlattice Structures
  - **GaAs/GaAsP**
  - GaAsSb
  - AlGaAs/GaAs
  - Distributed Bragg Reflector for high QE

## Variations

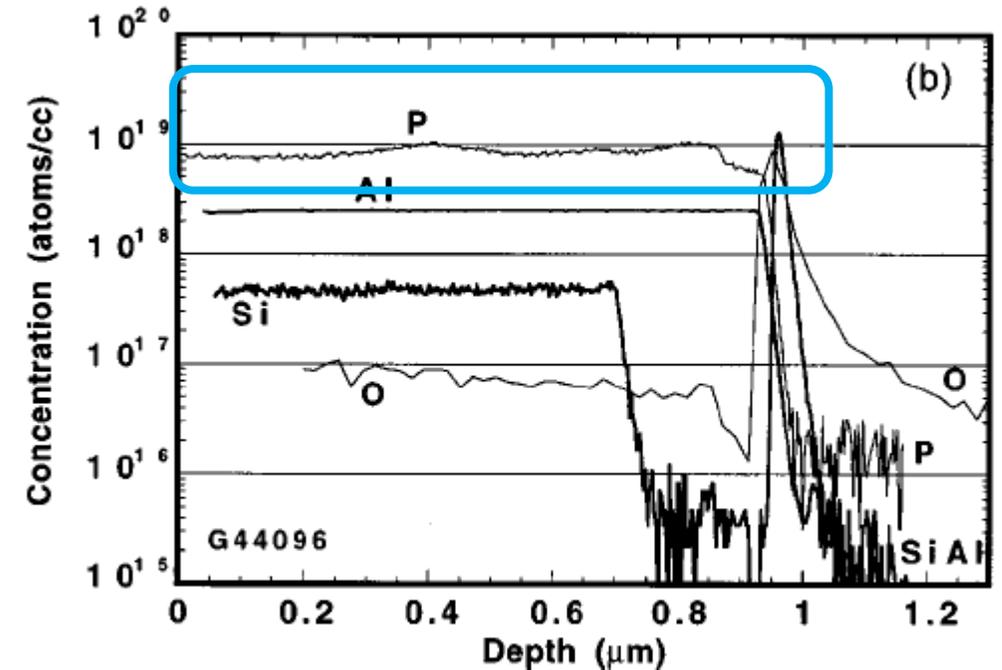
- Quantum Well thickness
- Barrier thickness
- Strain layer concentration
- Number of periods



AlGaAs/GaAs, A. Moy 2009

# Technical Challenges of Growing GaAs/GaAsP using GSMBE

- GSMBE (Gas source MBE) uses crackers for AsH<sub>3</sub> (arsine) and PH<sub>3</sub> (phosphine)
  - Both gasses Toxic, Flammable
  - Phosphorus grows on MBE walls
    - Generates phosphine gas & phosphoric acid when venting
    - Absorbs water and has high water vapor pressure when pumped back down
    - Residue cannot be scraped off - ignites
      - Careful degassing can solve this
  - Phosphine residue can cause high background in subsequent samples

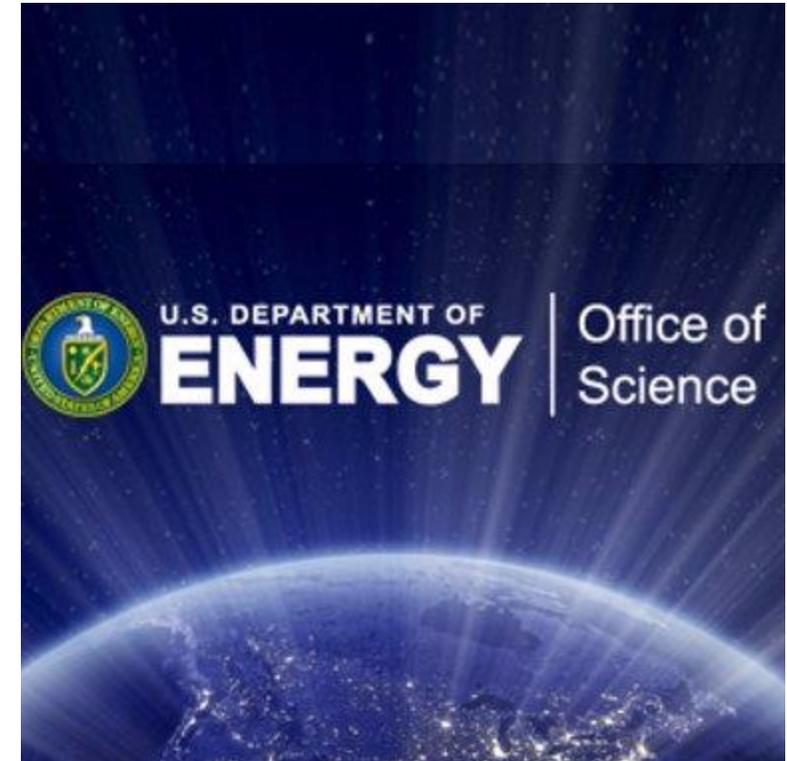


*SIMS of AlGaAs grown after Phosphorus contamination*

W.E.Hoke and P.J. Lemonias JVSTB **17**  
1999, p. 2009.

# SBIR research program lifetime

- SBIR Program Goals include
  - Stimulate technological innovation
  - **Use small business to meet Federal R/R&D needs**
- SBIR Phases
  - Phase I explores the feasibility of innovative concepts with awards up to \$250,000 and 12 months.
  - Phase II is the principal R&D effort, with awards up to \$1,600,000 and 2 years.
  - *Phase III: pursue commercial applications of their R&D with non-SBIR/STTR funding.*
    - Market for high polarization photocathode material is small
    - Commercialization not (yet?) financially viable



# Main Goal: New growth method to restore photocathode supply

- DOE Funding Opportunity 20-2310
  - CBE (Chemical Beam Epitaxy)
    - Jefferson Lab:
      - Marcy Stutzman
    - University of California Santa Barbara
      - Chris Palmstrøm and Aaron Engel
- Investigate Chemical Beam Epitaxy for growing high polarization, strained superlattice photocathodes



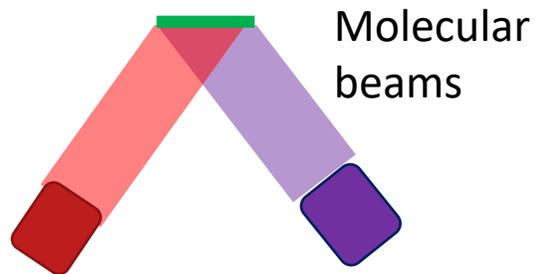
# MBE, GSMBE, CBE and MOCVD

## MBE

Gas Source  
Molecular Beam  
Epitaxy

elemental As, P, Ga

- Pressure  $\sim 10^{-8}$  mbar
- Growth rates  $\sim 1 \mu\text{m/hr}$
- Very precise control

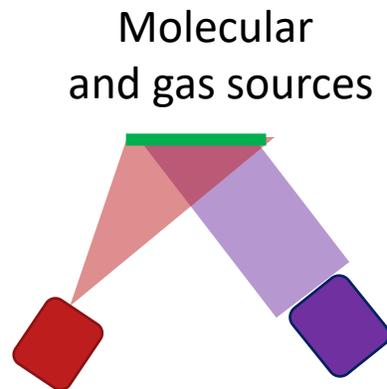


## GSMBE

Gas Source  
Molecular Beam  
Epitaxy

$\text{AsH}_3$ ,  $\text{PH}_3$ ,  
elemental Gallium

**Used at SVT**

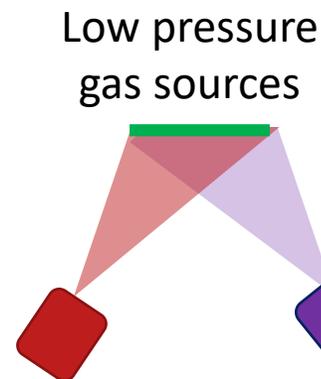


## CBE

Chemical Beam Epitaxy

$\text{AsH}_3$ ,  $\text{PH}_3$ , triethyl  
gallium (TEGa) or  
elemental Gallium

- Pressure  $< 10^{-4}$  mbar
- Growth rates  $0.5\text{-}1 \mu\text{m/hr}$



## MOCVD

Metal organic chemical  
vapor deposition

$\text{AsH}_3$ ,  $\text{PH}_3$ , trimethylgallium  
(TMGa)

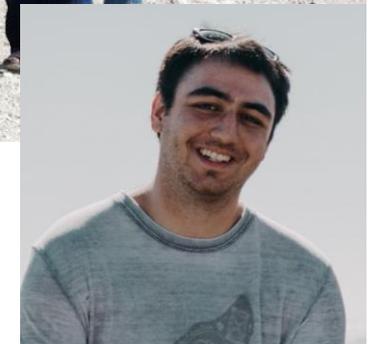
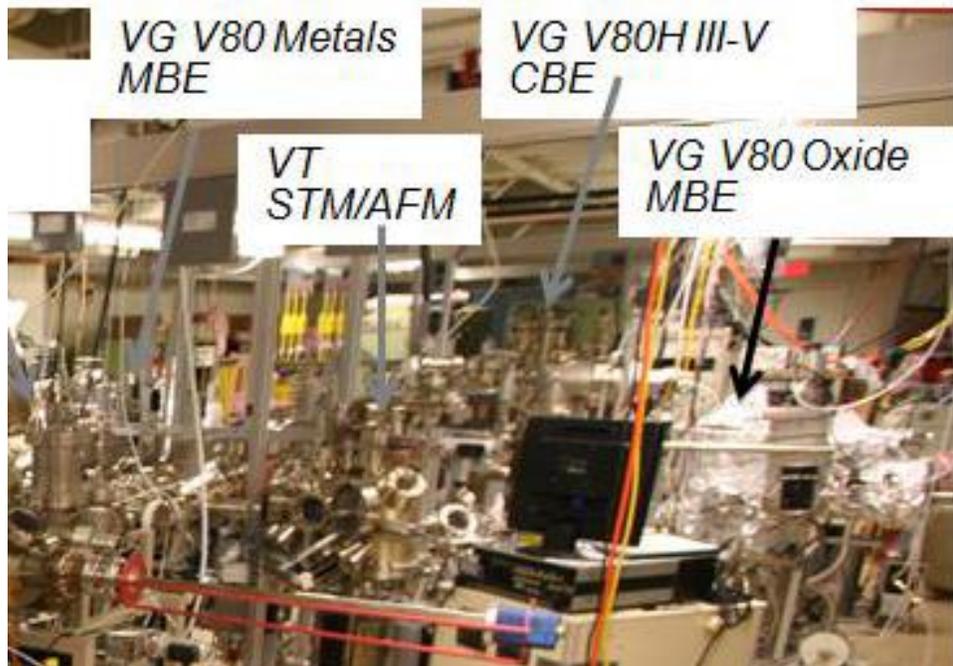
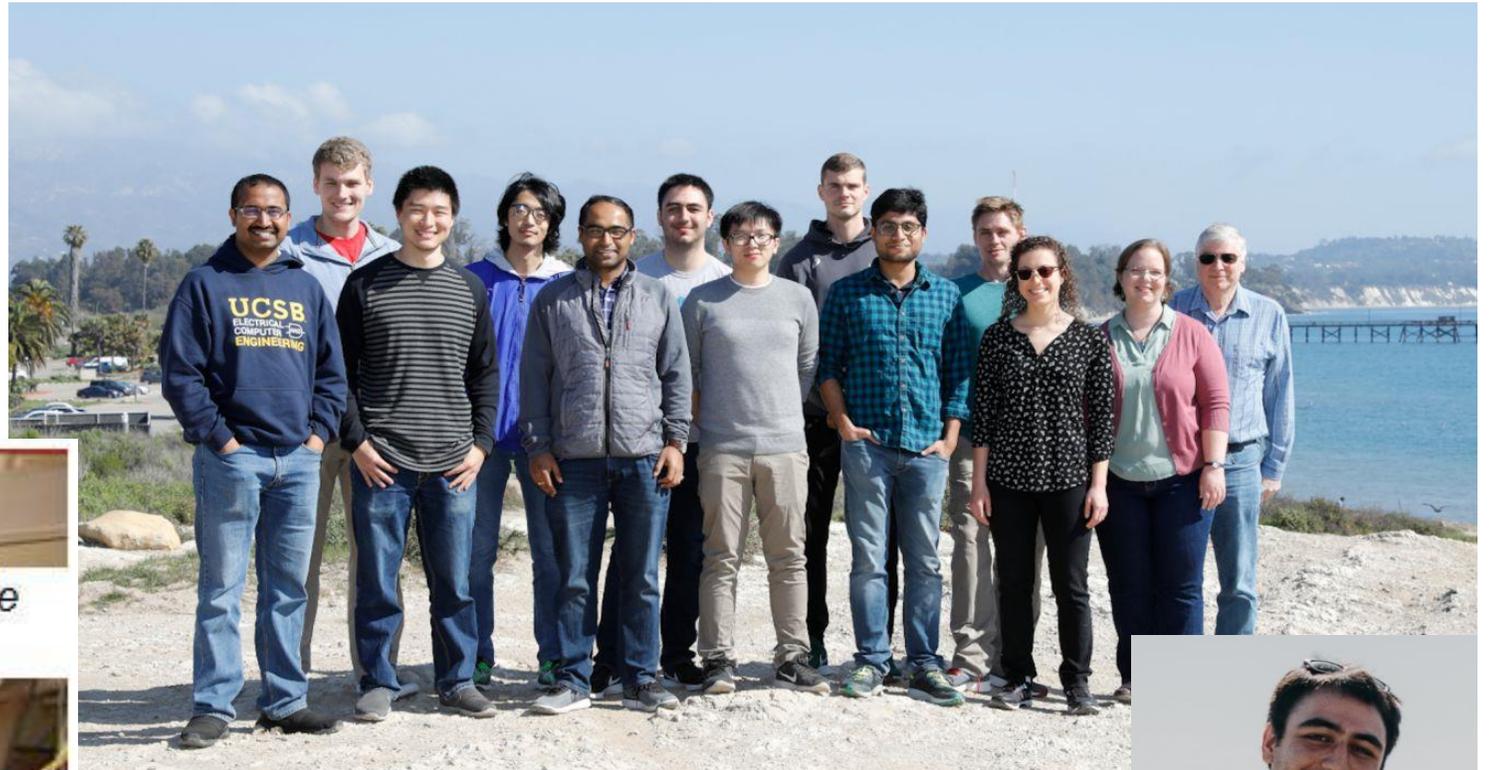
- Pressures  $> 100$  mbar during growth
- Growth Rates  $10 \mu\text{m/hr}$
- Traditionally difficult to get sharp interfaces



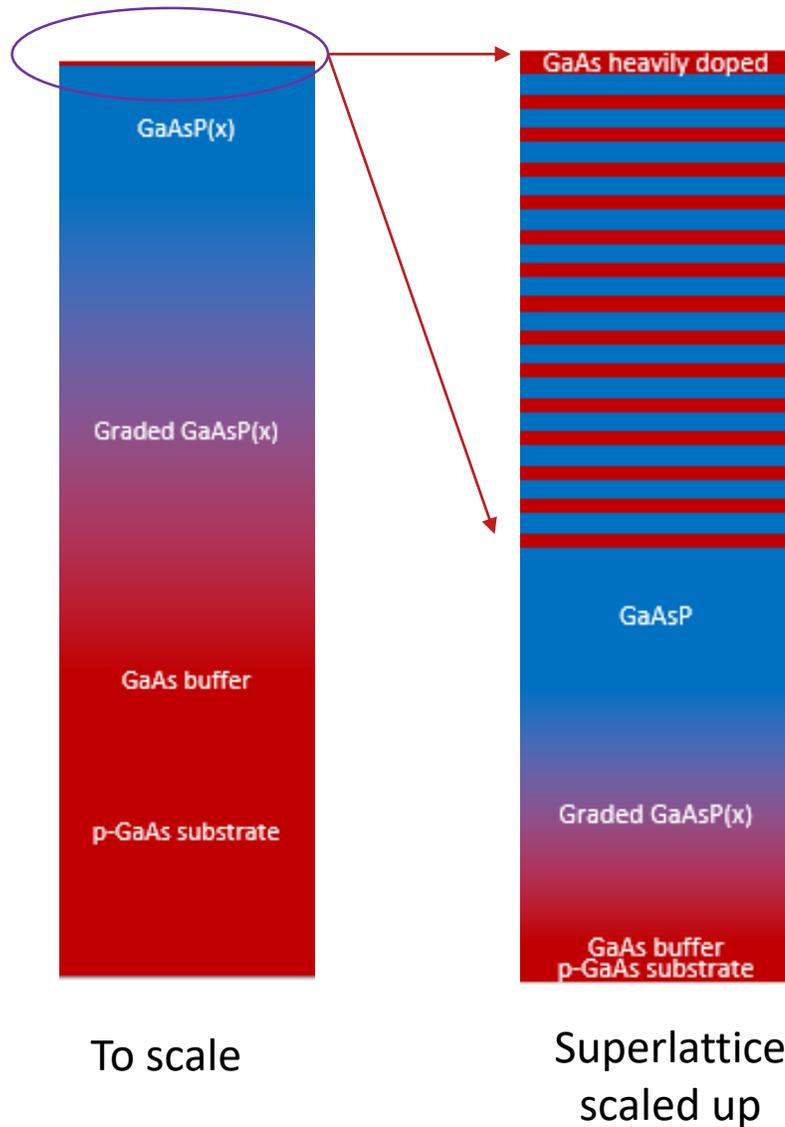
# CBE: Photocathode progress

Chris Palmstrøm Group, UCSB

- Aaron Engel, graduate student
- Chemical Beam Epitaxy System



# Wafer growth



- Epitaxial Buffer Layer grown on GaAs
- Graded GaAs to  $\text{GaAs}_{(1-x)}\text{P}_x$
- $\text{GaAs}_{(1-x)}\text{P}_x$  layer
- Superlattice
- Heavily doped top layer

## Parameters to vary

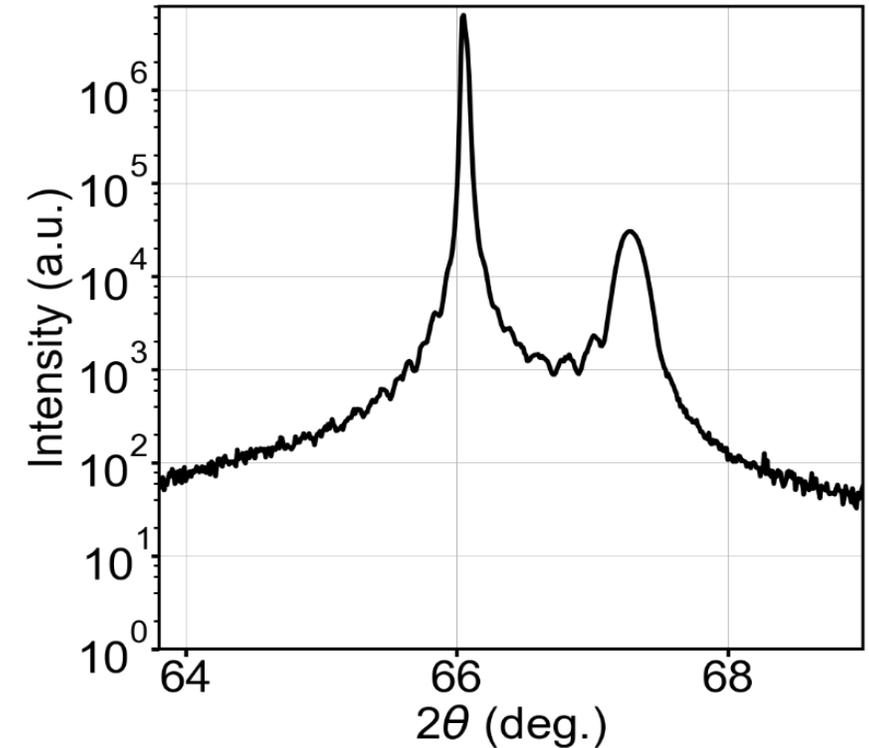
- Substrate Temperature
- Source Temperature/Pressures
- Time
- Grading profile
- Underlying crystal orientation
- Superlattice layer thickness

# CBE: Strained Layer growth

- Start with  $\text{GaAs}_x\text{P}_{(1-x)}$  on GaAs
  - Temperature
  - gas pressures
- Testing
  - SIMS: Depth profile
  - XRD: Interface quality

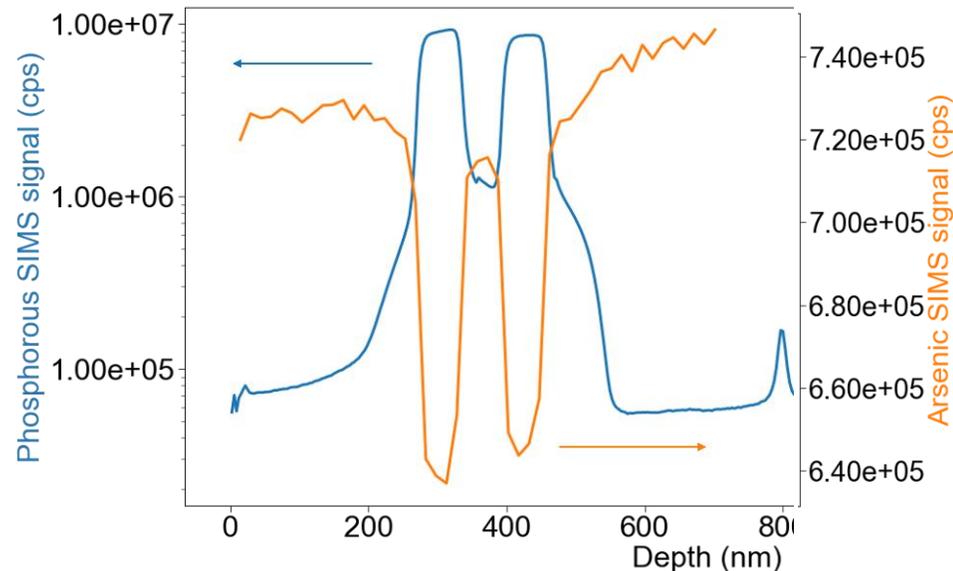
X-Ray Diffraction:  
1 micron  $\text{GaAs}_{0.75}\text{P}_{0.25}$  on GaAs

Testing analysis tools  
for interface quality



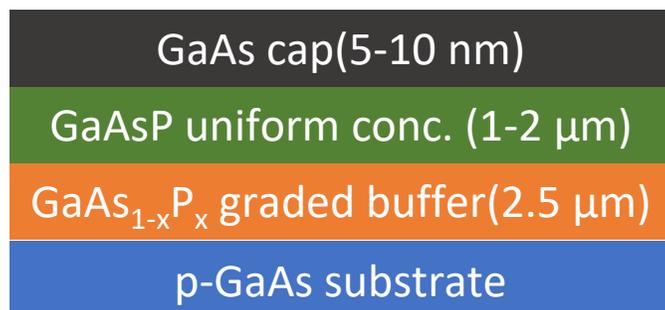
SIMS:  
Composition  
vs. Depth

GaAs:Be 250 nm
GaAs <sub>0.83</sub> P <sub>0.17</sub> :Be 50 nm
GaAs:Be 50 nm
GaAs <sub>0.83</sub> P <sub>0.17</sub> :Be 50 nm
GaAs:Be 4 μm
GaAs:Zn >10 <sup>18</sup>

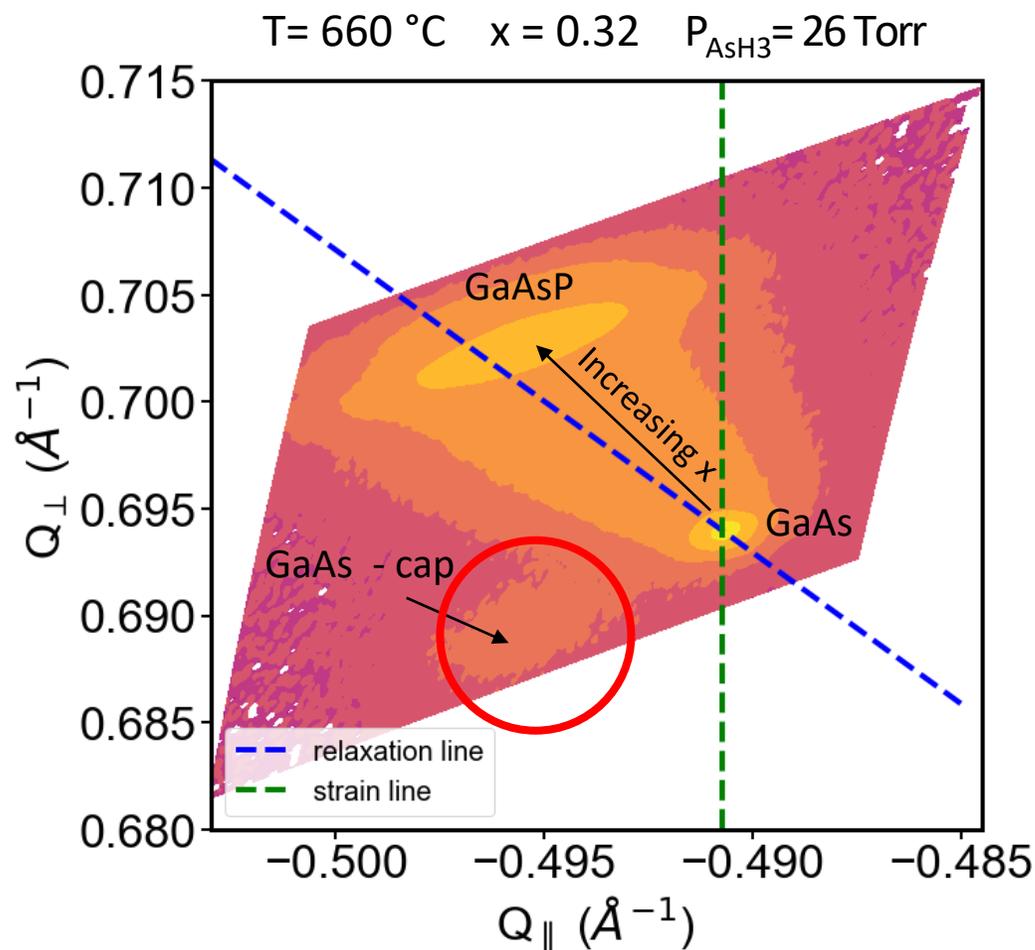


# CBE: Graded dopant layer growth

- Computerized control developed for GaAs->GaAsP graded layer
  - Smoothly varying Phosphorous content



- X-ray Reciprocal space mapping
  - Plot of lattice spacing during growth
  - Graded Layer with minimal strain
  - GaAs layer (5-10 nm) strained: lattice constant that of GaAsP



X-ray reciprocal space map for single 5-10 nm GaAs layer on GaAsP<sub>x</sub>

# CBE: Photocathode progress

## Next Steps

- Triethylgallium and phosphine create high vapor pressure background
  - Move to elemental Ga source?
  - Upgrade sample bonding from indium to gallium
- Grow photocathode material to test & test at JLab

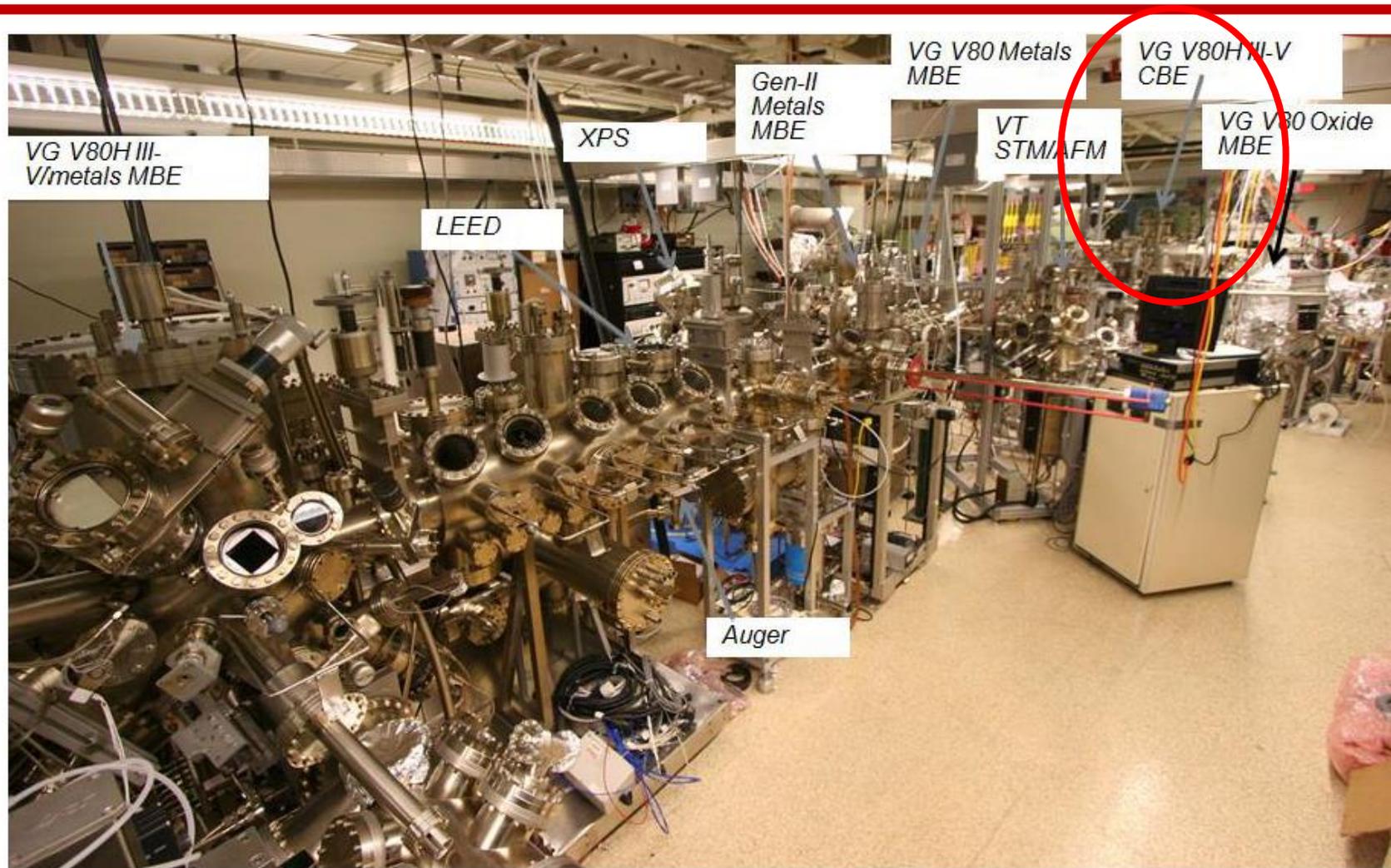


Figure 2 Semiconductor deposition system at Chris Palmstrom's lab at UCSB. The CBE system for the growth of this material is shown at the back and labelled "VG V80H III-V CBE".

# Budget Status

- FY20 budget request/received
  - \$276.2k / **\$129.2k**
  - \$93k unloaded / \$113.3 loaded to UCSB (vs. \$150k UCSB request)
  - Project scope reduced and delayed
- FY21 budget request/received
  - \$276.2k / **\$276.2k**
  - \$150k unloaded / \$187 loaded to UCSB
    - Graduate student
    - Supervisor
    - Materials and equipment use fees
  - JLab remainder
    - Design upgraded MicroMott polarimeter
    - Supplies for photocathode tests

	FY20	FY21	Totals
a) Funds allocated	\$126,200	\$276,200	\$402,400
b) Actual costs to date	\$110,414	0	\$110,414

# Project Goals

Tasks Year 1	2020 Q1	2020 Q2	2020 Q3	2020 Q4	2021 Q1	2021 Q2	2021 Q3	2021 Q4
• JLab: Replace MicroMott Polarimeter CEM								
• JLab: Train Student to use MicroMott (COVID delay)			x	x	x			
• JLab: Design upgrade for MicroMott	x	x	x	x	x			
• JLab: Build MicroMott Upgrade	x	x	x	x	x	x	x	x
• JLab: Polarization and QE measurements				x	x			
• JLab: High voltage gun tests								
• UCSB: Calibration runs	x							
• UCSB: Begin growing graded layers	x	x	x					
• UCSB: Grow superlattice layers to characterize thickness and interface	x	x						
• UCSB: Characterize the interfaces and composition at UCSB: SIMS and XRD								
• UCSB: Send initial material to JLab for testing				x				
• UCSB: Optimize for uniformity across wafer								
• UCSB: Grow and deliver superlattice photocathodes suitable for use at CEBAF								
• UCSB: Investigate DBR growth if extra time							x	x

Green: done  
 Blue: planned  
 x: delayed or eliminated

# Conclusion

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- Project milestone delays and scope reduction due to funding gap
- Graded layer grown successfully
  - Potentially reverting to solid source for gallium, same growth process same as SVT used
  - Good morphology and no unwanted strain in graded layer
- Superlattice interfaces characterized
  - Sharp definition seen in SIMS and XRD analysis
- Current work in progress to grow graded layer and superlattice for first test sample
- Anticipate receiving several high quality photocathodes by end of year

Questions?

# backup

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# Manouchehr's instructions

## PI Meeting Presentation Guidelines:

Each presentation should include the following information:

- Description of the project and the current status;
- Main goal of the project for which you received the **FY 2020- 121 Accelerator R&D award , and/or Lab Data call for AI/ML award.**
- A table showing annual budget and the total received to date (see below);
- A table showing major deliverables and schedule;
- Summary of expenditures by fiscal year (FY):
- There will be no written report or follow up actions required for this meeting.
- All talks will be posted on PI Exchange meeting page on NP website.
- **35 min talks should allow 7 min for Q/A and 30 min talks 5 min for Q/A**

	FY20	FY21	Totals
<b>a) Funds allocated</b>			
<b>b) Actual costs to date</b>			

1

*M. Farkhondeh, 2021 NP Accelerator R&D and AI/ML PI Meeting, Nov 30, 2021*

Marcy Stutzman, Annual NP Accelerator R&D and AI/ML  
PI Meeting, Nov. 30, 2021